TECHNOLOGY DAY May 11, 2016

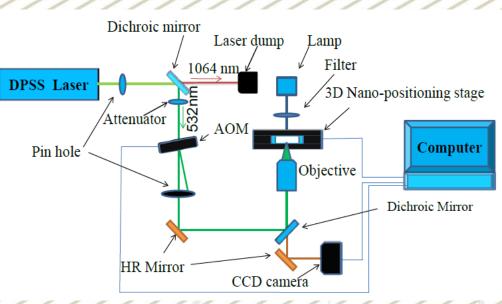


Fig.(1) Schematic of the system Fig.(2) System photograph ntensity Plot 1.0 () 1.0 Polymerization threshold

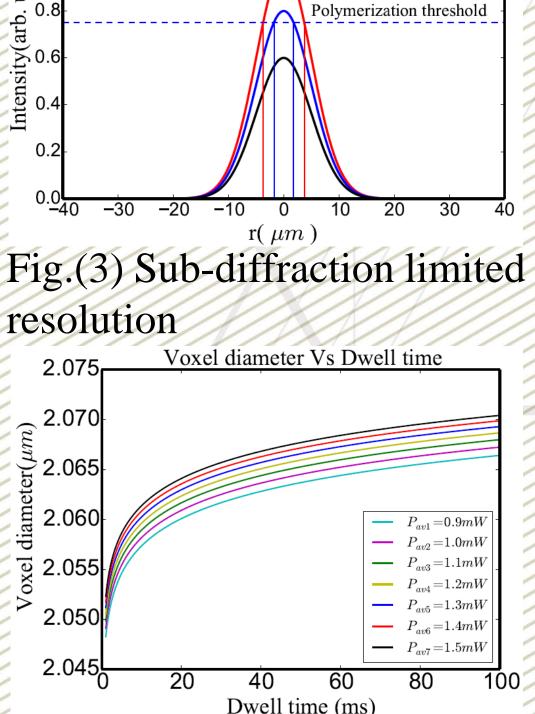


Fig.(4) Voxel diameter versus

dwell time & laser power

A two-photon laser writing system with sub-micrometer resolution has been developed. It uses a sub-nano second laser and commercially available photoresist and enhancer materials. This system is an inexpensive alternative with similar capabilities as a femtosecond based laser writer. It has much higher capabilities for 2-D structuring in terms of aspect ratio than conventional 2-D laser micro writers

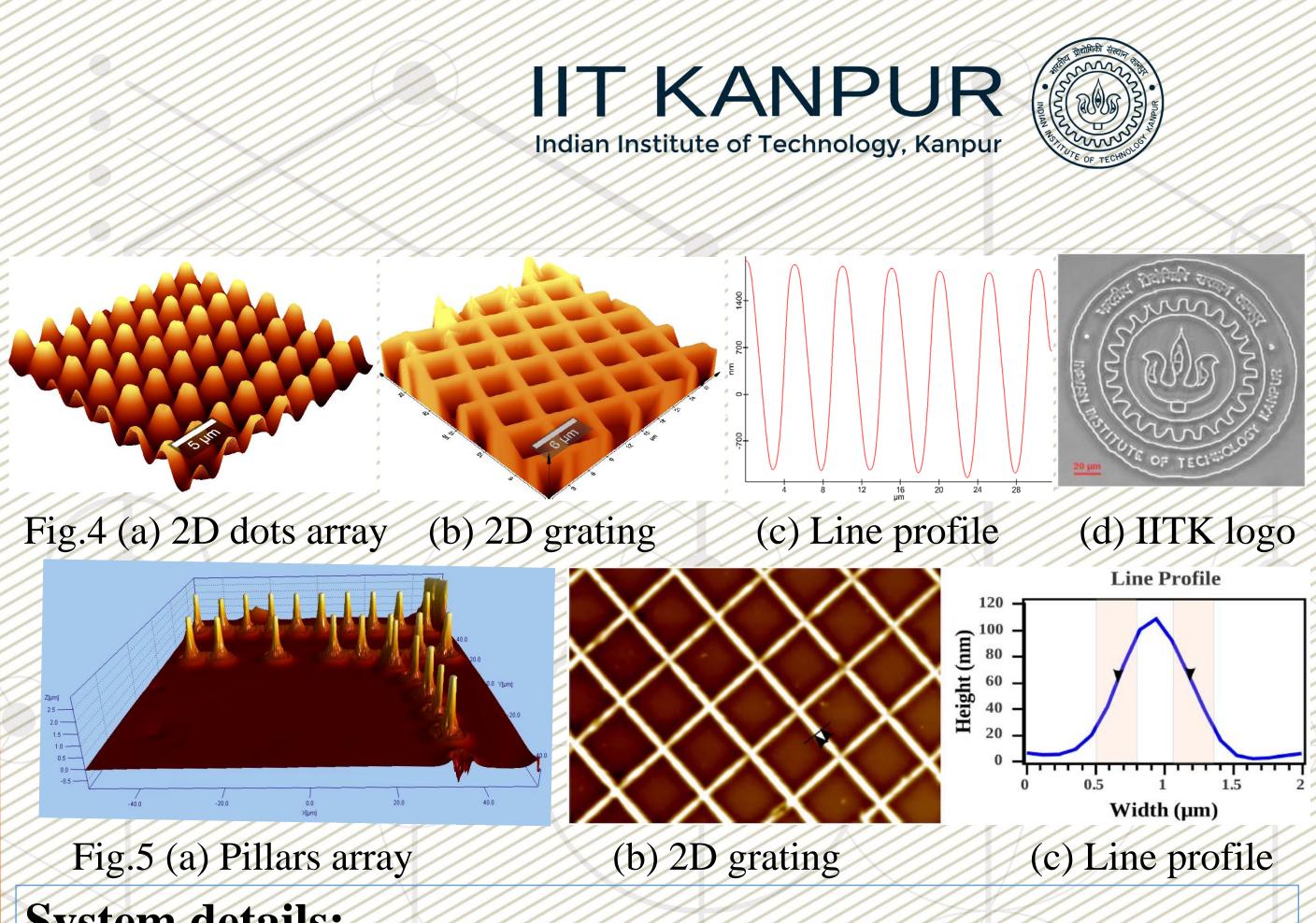
Applications / Markets: > Micro-optic and photonic devices: Microlenses, gratings, metamaterials.

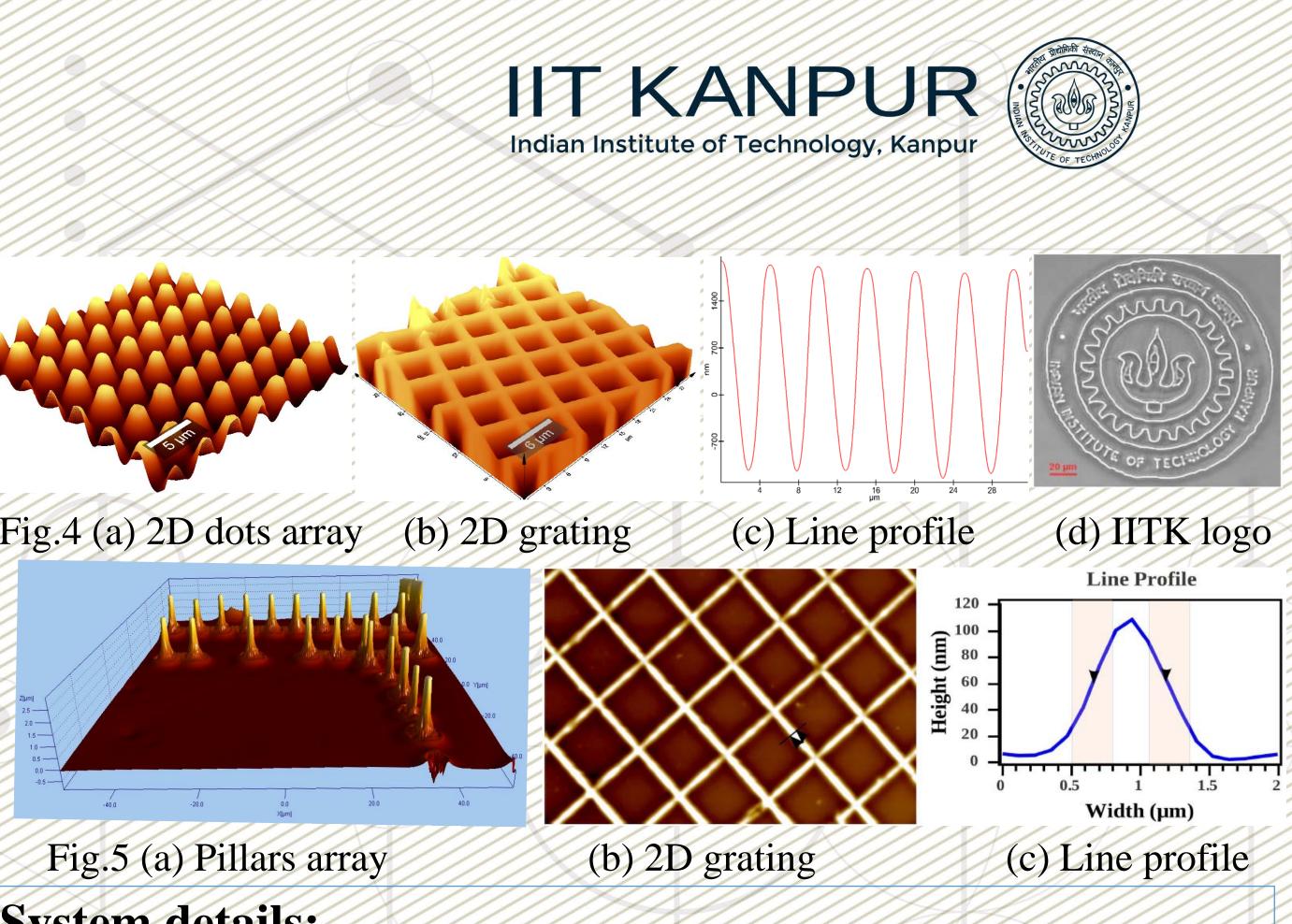
► Microfluidic devices: Filter elements, capillary pump, channels. >Micro rapid prototyping: Micro lens holder >Life sciences : Microneedles, scaffolds and boimemitics for tissue engineering, drug-delivery devices. >MEMS/NEMS: Micro-springs, micro gears, micro rotators. >Data storage: 3D optical data storage. >Electronic circuit board manufacturing. ► Microwave hybrid micro integrated circuits. Thus system has potential applications in the above mentioned fields and new applications are being explored. Here, we have used inexpensive sub nano-second laser and commercial available photoresists and photoinitiators for micro-fabrications. This clearly lays out new route for low cost fabrication systems and moving towards industrial rapid production systems.

Multiphoton 3-D laser microwriter with a sub-nanosecond laser

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3D photonic crystals, waveguides, sensors, microring-resonators,





System details:

Laser: Wavelength - 532 nm, pulse energy~0.2µJ, pulse width~ 700 ps, Rep rate 1-10 Khz. >Materials: Negative photoresists as SU-8, ARN-4340 with photoinitiator.

>Writing resolution: > 500 nm, depth few micro meters. \triangleright Stage: Piezo electric XYZ(3-D) nano-positioning stage with a travel range of 200 μ m × 200 μ m × 200 μ m and writing speed up to $2000 \,\mu\text{m/s}$ for fabrication of 3D micro-structures.

Novelty of technology: This technology has unique capability that can be employed for fabrication of highly complex 3-D microstructures with resolutions beyond diffraction limit.

Summary: An inexpensive two photon 3-D laser writing system as an alternative to femtosecond based laser writers with sub-micrometer resolution based on sub-nanosecond pulsed laser has been developed.

2D motorized stage with travel range of 7.5cm \times 12cm and writing speed up to 2 mm/s for large area fabrication.

Software: LabView software is used to simultaneously control the motion of piezoelectric stage and AO modulator(laser shutter).